

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants : Shin Hwa Li et al.
Filed : December 22, 2003
For : SEMICONDUCTOR STRUCTURE HAVING AN
IMPROVED PRE-METAL DIELECTRIC STACK AND
METHOD FOR FORMING THE SAME

Docket No. : 98-P-009D1 (850063.529D1)

Date : December 22, 2003

Mail Stop Patent Application
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

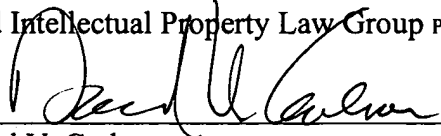
Commissioner for Patents:

In accordance with 37 C.F.R. §§ 1.56 and 1.97 through 1.98, applicants wish to make known to the Patent and Trademark Office the 25 references set forth on the attached Form PTO-1449. This application relies, under 35 U.S.C. § 120, on the earlier filing date of prior Application No. 09/632,388, filed August 3, 2000. The references listed on the attached Form PTO-1449 were submitted to and/or cited by the Patent and Trademark Office in this prior application and, therefore, are not required to be provided in this application. If the Examiner wishes, copies will be provided upon request. As to any reference supplied, applicants do not admit that it is "prior art" under 35 U.S.C. §§ 102 or 103, and specifically reserve the right to traverse or antedate any such reference, as by a showing under 37 C.F.R. § 1.131 or other method. Although the aforesaid references are made known to the Patent and Trademark Office in compliance with applicants' duty to disclose all information they are aware of which is believed relevant to the examination of the above-identified application, applicants believe that their invention is patentable.

Please acknowledge receipt of this Information Disclosure Statement and kindly make the cited references of record in the above-identified application.

Applicants believe this Information Disclosure Statement has been timely filed, however, the Director is authorized to charge any fee due by way of this Information Disclosure Statement to our Deposit Account No. 19-1090.

Respectfully submitted,
Seed Intellectual Property Law Group PLLC



David V. Carlson
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DVC:lcs

Enclosures:

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Form PTO-1449

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FORM PTO-1449 (REV.7-80)	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTY. DOCKET NO. 98-P-009D1 (850063.529D1)	APPLICATION NO.
INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)		APPLICANTS Shin Hwa Li et al.	
		FILING DATE December 22, 2003	GROUP ART UNIT

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	AA	4,983,546	01/08/91	Hyun et al.	438	800	
	AB	5,169,491	12/08/92	Doan	156	636	
	AC	5,437,763	08/01/95	Huang	216	18	
	AD	5,468,682	11/21/95	Homma	438	633	
	AE	5,485,035	01/16/96	Lin et al.	257	637	
	AF	5,503,882	04/02/96	Dawson	427	579	
	AG	5,518,962	05/21/96	Murao	438	624	
	AH	5,560,802	10/01/96	Chisholm	156	636.1	
	AI	5,567,661	10/22/96	Nishio et al.	438	800	
	AJ	5,607,880	03/04/97	Suzuki et al.	438	624	
	AK	5,661,084	08/26/97	Kuo et al.	438	624	
	AL	5,747,381	05/05/98	Wu et al.	438	624	
	AM	5,783,482	07/21/98	Lee et al.	438	624	
	AN	5,858,882	01/12/99	Chang et al.	438	761	
	AO	6,001,731	12/14/99	Su et al.	438	633	
	AP	6,110,831	08/29/00	Cargo et al.	438	692	
	AQ	6,127,261	10/03/00	Ngo et al.	438	633	
	AR	6,281,112	08/28/01	Sugiyama	438	624	

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		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION	
					YES	NO
	AS	0599317A1	06/01/94	EP		
	AT	09223740	08/26/97	Japan (Abstract only)		
	AU	08255791	10/01/96	Japan (Abstract only)		

EXAMINER

DATE CONSIDERED

* EXAMINER: Initial if reference considered, whether or not criteria is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant(s).

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	AE						
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	AG						
	AH						
	AI						
	AJ						

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		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION	
					YES	NO
	AK					
	AL					
	AM					
	AN					
	AO					

OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)

AV	Wolf, Stanley, PhD., Silicon Processing for the VLSI Era, Volume 2-Process Integration, Lattice Press, Sunset Beach, Volume 2: 334-337, 1990.
AW	Schaffer, W.J., et al., "BPSG Improves CPMP Performance for Deep Submicron Ics," Semiconductor International, 205-212, 1996.
AX	Armstrong, W.E., et al., "A Scanning Electron Microscope Investigation of Glass Flow in MOS Integrated Circuit Fabrication," Journal of the Electrochemical Society, Volume 121, No. 2, 307-310, 1974.
AY	Kerr, D.R., et al., "Stabilization of SiO ₂ Passivation Layers with P ₂ O ₅ ," IBM Journal of Research and Development, Volume 8, No. 4, 376-384, 1964.

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